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Attorney's Docket No.

09712-124001

Application No.

09/879,428

**Information Disclosure Statement
by Applicant**

(Use several sheets if necessary)

Applicant

Henry A. Hill

Filing Date

June 12, 2001

Group Art Unit

U.S. Patent Documents

| Examiner Initial | Desig. ID | Patent Number | Issue Date | Patentee | Class | Subclass | Filing Date If Appropriate |
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| JRA | AP | Badami V.B. et al., "Investigation of Nonlinearity in High Accuracy Heterodyne Laser Interferometry," 1997 Proceedings, Vol. 16, pp. 153-156. |
| | AQ | Wu, C.M. et al., "Analytical Modeling of the Periodic Nonlinearity in Heterodyne Interferometry" Applied Optics, Vol. 37, No. 28, October 1, 1998, pp. 6696-6700. |
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Examiner Signature

Date Considered

EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.